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Docket No.: SON-1908/DIV
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Takeshi Nogami et al.

Application No.: 10/759,194

Confirmation No.: 7751

Filed: January 20, 2004

Art Unit: 2823

For: **METHOD FOR PRODUCING
SEMICONDUCTOR DEVICE, POLISHING
APPARATUS, AND POLISHING METHOD**

Examiner: F. L. Toledo

*Please
enter
12/23/06*

AMENDMENT AFTER FINAL ACTION (37 C.F.R. SECTION 1.116)

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated January 9, 2006, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 11 of this paper.